

Application No. 10/722,602
Reply to Office Action of November 30, 2005

AMENDMENTS TO THE ABSTRACT

Please replace the Abstract with the Abstract attached hereto on a separate page.

ABSTRACT

An internal member of a plasma processing vessel includes a base material and a film formed by thermal spraying of ceramic on a surface of the base material. The film is formed of ceramic which includes at least one kind of element selected from the group consisting of B, Mg, Al, Si, Ca, Cr, Y, Zr, Ta, Ce and Nd. In addition, at least a portion of the film is sealed by a resin.